

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Toshihide TSUBATA et al. Application No.: 10/595,640 Confirmation No.: 3891 Filing or 371(c) Date: May 2, 2006 Title: TRANSISTOR AND CVD APPARATUS USED TO DEPOSIT GATE INSULATING FILM THEREOF	Art Unit: 2818 Examiner: E. Taylor
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AMENDMENT

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Office Action dated July 26, 2007, the period for response to which has been extended to November 26, 2007, by the accompanying Petition for One-Month Extension of Time, please amend the above-identified application as follows:

- ☐ **Amendments to the Specification** begin on page of this paper.
- ☒ **Amendments to the Claims** are reflected in the listing of the claims which begins on page **2** of this paper.
- ☐ **Amendments to the Drawings** begin on page of this paper and include an attached replacement sheet. An **Appendix** including the amended drawing figures is attached following page of this paper.
- ☒ **Remarks/Arguments** begin on page **4** of this paper.
- Please note, if a box is not checked, then no corresponding amendment is being made.